

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket: 8183

Applicant(s): KOOPS, Hans Wilfried Peter

United States Filing Date: July 28, 2003

United States Application Serial No. : 10/628,174

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**AUG 04 2005**

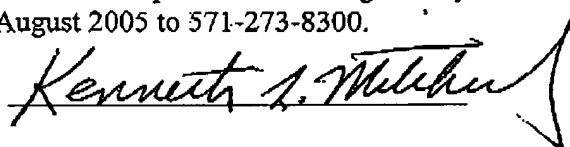
Title: PROCEDURE FOR ETCHING OF MATERIALS AT THE SURFACE WITH  
FOCUSSED ELECTRON BEAM INDUCED CHEMICAL REACTION AT SAID SURFACE

Examiner: Olsen, Allan W  
Art Unit: 1763

August 4, 2005

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

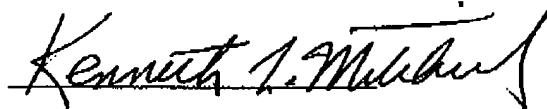
Fax Certification: I hereby certify that this correspondence is being sent by fax to the  
Commissioner for Patents on this 4<sup>th</sup> day of August 2005 to 571-273-8300.



Kenneth L. Mitchell, Reg. No. 36873

RESPONSE TO ELECTION

This is in response to the office action dated July 7, 2005. Applicant wishes to elect the  
invention of Group I, claims 1-3, 19-41 and 43.



Kenneth L. Mitchell, Reg. No. 36,873  
Woodling, Krost and Rust  
9213 Chillicothe Road  
Kirtland, Ohio 44094  
440-256-4150 p  
440-256-7453 f  
Clevepat@aol.com

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